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IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE

APPLICANTS: Dan Meisburger, Alan D. Brodie, Zhong-Wei Chen, Jack Y. Jau,
Paul Sandland, Richard Simmons, Dave E. A. Smith, Hans Dohse,
Dennis G. Emge, John Greene, Lee Veneklasen, Ming-Yie Ling,
Surendra G. Lele, Kirkwood Rough

APPLICATION NO.: 10/801,362

FILING DATE: March 15, 2004

TITLE: Inspecting Optical Masks With Electron Beam Microscopy

EXAMINER: Unknown

GROUP ART UNIT: 1756

ATTY. DKT. NO.: 22120-08965

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner For Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below:

Dated: March 23, 2005

By: Laura Majerus
Laura A. Majerus, Reg. No. 33,417

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P.O. BOX 1450
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3rd REQUEST FOR CORRECTED FILING RECEIPT

SIR:

Enclosed is a copy of the Official Filing Receipt. It contains the following errors:

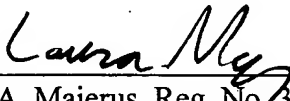
1. The above-referenced application is a continuation of pending serial no. 09/502,534, filed on February 10, 2000; the subject matter of the present reissue is related to co-pending reissue serial no. 09/502,120, filed on February 10, 2000, as evidenced by the third page of the Preliminary Amendment filed March 15, 2004 in this matter, a copy of which is enclosed.

This Filing Receipt should be corrected to indicate the missing Continuing Data that this application "**This application is a CON of 09/502,534 filed 02/10/2000**, which is a REI of 08/606,854...."

Please issue a corrected Filing Receipt rectifying this error.

Respectfully submitted,
DAN MEISBURGER, ET AL.

Dated: March 23, 2005

By: 
Laura A. Majerus, Reg. No. 33,417
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UNITED STATES PATENT AND TRADEMARK OFFICE

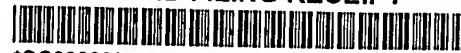
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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/801,362	03/15/2004	1756	2254	22120-08965	20	57	10

Laura A. Majerus, Esq.
 Finwick & West LLP
 Two Palo Alto Square
 Palo Alto, CA 94306



CONFIRMATION NO. 4849
 CORRECTED FILING RECEIPT



OC000000015354031

Date Mailed: 03/04/2005

Receipt is acknowledged of this reissue Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Dan Meisburger, San Jose, CA;
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 Zhong-Wei Chen, San Jose, CA;
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 Paul Sandland, Residence Not Provided;
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 Ming-Yie Ling, Saratoga, CA;
 Surendra G. Lele, Cupertino, CA;
 Kirkwood Rough, Residence Not Provided;

Power of Attorney:

Laura Majerus--33417
 Trinidad Arriola-Kern--44012

Domestic Priority data as claimed by applicant ~~CON~~ of 09/502,534 filed 02/10/2000, which is
 This application is a REI of 08/606,854 02/26/1996 PAT 5,717,204
 which is a CON of 08/252,763 06/02/1994 ABN
 which is a CIP of 07/889,460 05/27/1992 ABN

Foreign Applications

If Required, Foreign Filing License Granted: 08/04/2004

The country code and number of your priority application, to be used for filing abroad under the Paris Convention, is **US10/801,362**

Projected Publication Date: None, application is not eligible for pre-grant publication

Non-Publication Request: No

Early Publication Request: No

Title

Inspecting optical masks with electron beam microscopy

Preliminary Class

430

**LICENSE FOR FOREIGN FILING UNDER
Title 35, United States Code, Section 184
Title 37, Code of Federal Regulations, 5.11 & 5.15**

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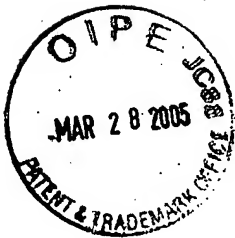
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IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE

APPLICANTS: Dan Meisburger, Alan D. Brodie, Zhong-Wei Chen, Jack Y. Jau,
Paul Sandland, Richard Simmons, Dave E. A. Smith, Hans
Dohse, Dennis G. Emge, John Greene, Lee Veneklasen, Ming-
Yie Ling, Surendra G. Lele, Kirkwood Rough

SERIAL NO.: Continuation of 09/502,534

PARENT FILING DATE: February 10, 2000

TITLE: Inspecting Optical Masks With Electron Beam Microscopy

EXAMINER: Unknown

GROUP ART UNIT: Unknown

ATTY. DKT. NO.: 22120-08965

CERTIFICATE OF MAILING

I hereby certify that this correspondence, including the enclosures identified herein, are being deposited with the United States Postal Service as Express Mail in an envelope addressed to: Mail Stop Patent Application, Commissioner For Patents, P. O. Box 1450, Alexandria, VA 22313-1450, on the date shown below. This correspondence is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service pursuant to 37 CFR 1.10: Express Mail No. EV 442673984 US.

Dated: March 15, 2004

By: Laura Majerus
Laura A. Majerus, Reg. No. 33,417

MAIL STOP PATENT APPLICATION
COMMISSIONER FOR PATENTS
P. O. BOX 1450
ALEXANDRIA, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

This application is a continuation of pending application number 09/502,534, filed on February 10, 2000, which was a reissue application for patent no. 5,717,204 issued February 10, 1998, which is a continuation of 08/252,763, which is a CIP of 07/889,460, and is in response to the Notice of Appeal filed August 14, 2003, which established a non-statutory period for filing an

appellate brief that expired on March 14, 2004 (a Sunday). A fee for a five-month extension of time is included herewith.

IN THE SPECIFICATION

After the section title "CROSS REFERENCE", but before the section title "FIELD OF THE INVENTION", please insert the following paragraph:

This application is a continuation of the U.S. Reissue Application Serial No. 09/502,534, the subject matter of the present reissue application is related to co-pending reissue application entitled Inspecting Optical Masks With Electron Beam Microscopy, said application having Serial No. 09/502,120, which reissue application was also filed on February 10, 2000. The reissue application, Serial No. 09/502,534, and the co-pending reissue application, Serial No. 09/502,120, are each a reissue of U.S. Application No. 08/606,854 filed February 26, 1996, now U.S. Patent No. 5,717,204, which is a continuation of 08/252,763, which is a CIP of 07/889,460.

Please delete the paragraph at col. 11, lines 19-37 and replace it with the following:

--The diameter of the scanning beam 100 and its current are determined by several factors. The angular emission from the source (1.0 [Ma]mA/steradians), and the aperture angle defined by final aperture 99 determine the beam current. The probe diameter is determined by aberrations in both lenses, which are designed for high excitation (field width/focal length) to minimize both spherical and chromatic aberration. The effect of beam interactions (i.e. statistical blurring due to repulsion between individual beam electrons) are also important in this high current system, accounting for about half the probe size on substrate 57. These effects are minimized by avoiding intermediate crossovers, by using a short beam path (40 cm.) and by using lenses with relatively large half angles at the source and substrate 57. To obtain a given spot size, the aperture diameter is chosen to balance all these effects while providing maximum



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006/PTO Rev. 10/95		U.S. Department of Commerce Patent and Trademark Office		Application Number	10/801,362		
TRANSMITTAL FORM <i>(to be used for all correspondence during pendency of filed application)</i>				Filing Date	March 15, 2004		
				First Named Inventor	Dan Meisburger		
				Group Art Unit Number	1756		
				Examiner Name	Unknown		
Total Number of Pages in This Submission		8	Attorney Docket Number		22120-08965		

ENCLOSURES (check all that apply)	
<input type="checkbox"/> Fee Transmittal Form (in duplicate). <input type="checkbox"/> Check Enclosed	<input type="checkbox"/> Issue Fee Transmittal
<input checked="" type="checkbox"/> Return Receipt Postcard	<input type="checkbox"/> Letter to Chief Draftsperson
<input type="checkbox"/> Response to Notice to File Missing Parts	<input type="checkbox"/> Formal Drawing(s): [] Sheet(s) of Figure(s) []
<input type="checkbox"/> Assignment & Recordation Cover Sheet	<input type="checkbox"/> Appeal Communication to Board of Appeals and Interferences
<input type="checkbox"/> Declaration	<input type="checkbox"/> Appeal Communication to Group (Appeal Notice, Brief, Reply Brief)
<input type="checkbox"/> Power of Attorney	<input type="checkbox"/> Certified Copy of Priority Document(s)
<input type="checkbox"/> Application Data Sheet	<input type="checkbox"/> After Allowance Communication to Group
<input type="checkbox"/> Information Disclosure Statement & PTO/SB/08A <input type="checkbox"/> Copies of IDS Cited References	<input checked="" type="checkbox"/> Copy of Corrected Filing Receipt
<input checked="" type="checkbox"/> 3rd Request for Corrected Filing Receipt	<input checked="" type="checkbox"/> Copy of pages 1-3 of Preliminary Amendment
<input type="checkbox"/> Request for Correction of Recorded Assignment	<input type="checkbox"/>
<input type="checkbox"/> Amendment/Response: [] Page(s) <input type="checkbox"/> After Final	<input type="checkbox"/>
<input type="checkbox"/> Status Request	<input type="checkbox"/>
<input type="checkbox"/> Revocation and Substitute Power of Attorney	<input type="checkbox"/>
REMARKS:	

SIGNATURE OF ATTORNEY OR AGENT			
Signature:	<i>Laura Majerus</i>		
Attorney/Reg. No.:	Laura A. Majerus, Reg. No. 33,417	Dated:	March 23, 2005

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Signature:	<i>Laura Majerus</i>		
Typed or Printed Name:	Laura A. Majerus	Dated:	March 23, 2005
Express Mail Mailing Number (optional):			